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## FOREIGN PATENT DOCUMENTS

10/550040

Examiner Initials	Cite No.	Document Number (country code, no., kind code (if known))	Publication Date	Name of Patentee or Applicant	Pages, columns, lines where relevant passages appear	T
	12.	JP 2004-034270	02/05/2004	II et al.		
	13.	JP 2003-073859	03/12/2003	Wada et al.		
	14.	JP 2003-045325	02/14/2003	Hatai et al.		
	15.	EP 1319948 A2	06/18/2003	Dong		

## OTHER DOCUMENTS

Examiner Initials	Cite No.	Include Author (in CAPITAL LETTERS), Title, Journal, Date, Pertinent Pages, Etc.	T
	16.	Commonly-assigned, co-pending U.S. Patent Application entitled, "Methods for Nanoscale Structures from Optical Lithography and Subsequent Lateral Growth," (Serial No. not yet assigned) (filed September 21, 2005).	
	17.	International Search Report and Written Opinion in PCT Application No. PCT/US04/08724 (November 19, 2004).	
	18.	International Preliminary Report on Patentability in PCT Application No. PCT/US04/08724 (May 31, 2005).	
	19.	International Search Report in PCT Application No. PCT/US04/08725 (February 28, 2005)	

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\*Examiner Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /B.K./